

ABSTRACT OF THE DISCLOSURE

- 5 A wafer carrier enabling a wafer of different size and/or shape to be processed in a process tool configured for processing a wafer of a predetermined size and/or shape, wherein the wafer carrier has such predetermined size and/or shape and includes at least one recess therein having the different size and/or shape. The wafer carrier enables the use in a process tool (e.g., a semiconductor epitaxial thin film deposition reactor such as a
- 10 single wafer reactor) of differently sized wafers than those for which the process tool is designed.